



BSI Standards Publication

Semiconductor devices - Micro-electromechanical devices

Part 30: Measurement methods of electro-mechanical conversion characteristics of MEMS piezoelectric thin film

National foreword

This British Standard is the UK implementation of IEC 62047-30:2017.

The UK participation in its preparation was entrusted to Technical Committee EPL/47, Semiconductors.

A list of organizations represented on this committee can be obtained on request to its secretary.

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